



Serial No. 09/899,784

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Patent Application of

Inventor(s): Dong-Su Kim

Group Art Unit: 2823

Serial No.: 09/899,784

Examiner: Toledo, Fernando L

Filing Date: July 5, 2001

For: Method of Fabricating Silica Microstructures

Box: AF
Assistant Commissioner for Patents
Washington, D.C. 20231

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AMENDMENT

Sir:

In response to the Final Office Action dated December 27, 2002, please amend the above-identified application as follows (a marked-up version is attached herein) with a one month extension.

A check in the amount of \$110.00 is enclosed to cover the one-month extension herein requested.

IN THE SPECIFICATION

Please amend the specification as follows:

Page 1, in the paragraph beginning on line 5, change as follows:

C1
This application claims priority to an application entitled "Method of Fabricating Silica Microstructures", filed in the Korean Intellectual Property Office on July 6, 2000 and assigned Serial No. 2000-38692, the contents of which are hereby incorporated by reference.